

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Divisional Application of Serial No. )  
09/812,688, filed March 21, 2001, of: )  
Masamitsu ITOH et al. ) Group Art Unit: To be Assigned  
Application No.: To be Assigned ) Examiner: To be Assigned  
Filed: Herewith )  
For: PATTERN FORMATION )  
MATERIAL, PATTERN )  
FORMATION METHOD, AND )  
EXPOSURE MASK FABRICATION )  
METHOD )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), Applicants bring to the attention of the Examiner the documents listed on the attached PTO 1449. This Information Disclosure Statement is being filed together with the above-referenced divisional application.

Copies of the listed documents were previously submitted in a prior application, Application No. 09/812,688, filing date March 21, 2001, upon which Applicants rely for the benefits provided in 35 U.S.C. § 120. Applicants respectfully request that the Examiner consider the listed documents and indicate that they were considered by making appropriate notations on the attached form.

The following is a concise statement of relevance of the non-English language documents:

1. Japanese Patent Application No. 8-262721
2. Japanese Patent Application No. 9-6002
3. Japanese Patent Application No. 9-6003
4. Japanese Patent Application No. 9-22117
5. Japanese Patent Application No. 9-127698
6. Japanese Patent Application No. 10-10738
7. Japanese Patent Application No. 9-219355

Japanese Patent Application numbers 1-7 disclose resist materials for optical lithography. In addition, Japanese Patent Application Nos. 9-6002 and 8-262721 were cited by the Examiner as an Office Action dated August 14, 2003.

8. Japanese Patent Application NO. 11-271965 disclosed a resist process for electron beam lithography. In addition, Japanese Patent Application No. 11-271965 and a partial machine translation thereof were cited by the Examiner in an Office Action dated August 14, 2002.

In lieu of a statement of relevance or translation of the non-English documents, an English language version of a search report from the Patent Office in a corresponding application citing these documents and setting forth the relevance thereof is enclosed.

In lieu of a statement of relevance or translation of the non-English documents Japanese Patent Application Nos. 11-231542, 11-218925, and 11-282166, an English

language version of a search report from the Korean Patent Office in a corresponding application citing these documents and setting forth the relevance thereof is enclosed.

In addition, in lieu of a statement of relevance or translation of the non-English documents Japanese Patent Application Nos. 2000-66405, 9-179301, and 11-15163, an English language version of a search report from the Japanese Patent Office in a corresponding application citing these documents and setting forth the relevance thereof is enclosed.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: September 22, 2003

By: Richard V. Burgujian Reg 24,014  
for Reg. No. 31,744

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
[www.finnegan.com](http://www.finnegan.com)

## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	4329.2543-01	Appln. No.	n/a
Applicant	Masamitsu ITOH et al.		
Filing Date	September 22, 2003	Group:	n/a

U.S. PATENT DOCUMENTS							
Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
		5,962,180	10/5/99	Iwanaga et al.			
		5,985,524	11-1999	Allen et al.			
		6,380,317	04-2002	Malik et al.			

FOREIGN PATENT DOCUMENTS							
		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
		WO 99/27418	6/3/99	PCT			
		8-262721	10/11/96	Japan			No
		9-6002	1/10/97	Japan			No
		9-6003	1/10/97	Japan			No
		9-22117	1/21/97	Japan			No
		9-127698	5/16/97	Japan			No
		10-10738	1/16/98	Japan			No
		9-219355	8/19/97	Japan			No
		11-271965	10/8/99	Japan			No
		11-231542	08/1999	Japan			No
		11-218925	08/1999	Japan			No
		11-282166	10/1999	Japan			No
		2000-66405	03/03/2000	Japan			No
		9-179301	07/11/1997	Japan			No
		11-15163	01/22/1999	Japan			No

## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	4329.2543-01	Appln. No.	n/a
Applicant	Masamitsu ITOH et al.		
Filing Date	September 22, 2003	Group:	n/a

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
	English language translation of an Office Action from the Chinese Patent Office dated June 6, 2003.

Examiner	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce